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Notice of Allowability	Application No.	Applicant(s)	
	10/659,337	HAEMATSU, HITOSHI	
	Examiner	Art Unit	
	Pamela E. Perkins	2822	
The MAILING DATE of this communication appeals all claims being allowable, PROSECUTION ON THE MERITS IS herewith (or previously mailed), a Notice of Allowance (PTOL-85) NOTICE OF ALLOWABILITY IS NOT A GRANT OF PATENT R of the Office or upon petition by the applicant. See 37 CFR 1.313	(OR REMAINS) CLOSED in this app or other appropriate communication IGHTS. This application is subject to	olication. If not include will be mailed in due of	d course. THIS
1. This communication is responsive to the filing of the RCE	on 3 January 2006.		
2. The allowed claim(s) is/are <u>1-4</u> .			
 Acknowledgment is made of a claim for foreign priority unally all b) Some* c) None of the: All b) Some* c) None of the: Certified copies of the priority documents have Certified copies of the priority documents have Copies of the certified copies of the priority do International Bureau (PCT Rule 17.2(a)). * Certified copies not received: Applicant has THREE MONTHS FROM THE "MAILING DATE" 	e been received. e been received in Application No ecuments have been received in this i	national stage applicat	
noted below. Failure to timely comply will result in ABANDONN THIS THREE-MONTH PERIOD IS NOT EXTENDABLE. 4. A SUBSTITUTE OATH OR DECLARATION must be subm		'S AMENDMENT or NO	OTICE OF
INFORMAL PATENT APPLICATION (PTO-152) which give			
5. CORRECTED DRAWINGS (as "replacement sheets") mus	st be submitted.		
(a) including changes required by the Notice of Draftspers	son's Patent Drawing Review (PTO-	948) attached	
1) hereto or 2) to Paper No./Mail Date	·		
(b) including changes required by the attached Examiner' Paper No./Mail Date	s Amendment / Comment or in the O	office action of	
Identifying indicia such as the application number (see 37 CFR 1 each sheet. Replacement sheet(s) should be labeled as such in t			back) of
 DEPOSIT OF and/or INFORMATION about the depo- attached Examiner's comment regarding REQUIREMENT 			ote the
Attachment(s) 1. Notice of References Cited (PTO-892)	5. ☐ Notice of Informal P	atent Application (PTC)-152)
2. Notice of Draftperson's Patent Drawing Review (PTO-948)	6. Interview Summary		
3. Information Disclosure Statements (PTO-1449 or PTO/SB/0	Paper No./Mail Dat 08), 7.		
4. Examiner's Comment Regarding Requirement for Deposit of Biological Material	8. Examiner's Stateme	ent of Reasons for Allow	wance
		Michael Trinin	
		Primary Examina	9 7

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DETAILED ACTION

This office action is in response to the filing of the RCE on 3 January 2006. Claims 1-4 are pending.

Allowable Subject Matter

Claims 1-4 are allowed.

Reasons for Allowance

The following is an examiner's statement of reasons for allowance: prior art does not anticipate, teach, or suggest a manufacturing method of a semiconductor device where a plurality of electrodes are formed on a front face of a semiconductor chip; covering the front face of the semiconductor chip with a resin insulating film; covering all of an upper surface and side surfaces of the resin insulating film with a metal protective film so that the metal protective film contacts the resin insulating film and extends to a surface of the semiconductor chip; and providing an electrical connecting portion at a reverse face of the semiconductor chip, wherein the electrical connecting portion is connected to at least any of the plurality of electrodes on the front face of the semiconductor chip.

For example, Harumi (JP 61019154) discloses a manufacturing method of a semiconductor device where an electrode is formed on a front face of a semiconductor chip; covering the front face the semiconductor chip with a resin insulating film; and

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covering all of an upper surface and side surfaces the resin insulating film with a metal protective film.

However, Harumi does not disclose, anticipate, teach, or suggest covering all of an upper surface and side surfaces of the resin insulating film with a metal protective film so that the metal protective film contacts the resin insulating film and extends to a surface of the semiconductor chip; and providing an electrical connecting portion of at least any of the plurality of electrodes at a reverse face of the semiconductor chip.

Hajime (JP 08107120) discloses a manufacturing method of a semiconductor device where a plurality of electrodes are formed on front face of a semiconductor chip; covering the front face of the semiconductor chip with a metal protective film, wherein a space is left between the front face of the semiconductor chip and the metal protective film; and providing an electrical connecting portion of at least any of the plurality of electrodes at a reverse face of the semiconductor chip.

However, Hajime does not disclose, anticipate, teach or suggest covering the front face of the semiconductor chip with a resin insulating film; and covering all of an upper surface and side surfaces of the resin insulating film with a metal protective film so that the metal protective film contacts the resin insulating film and extends to a surface of the semiconductor chip.

The prior art made of record in this action does not anticipate, teach, or suggest a manufacturing method of a semiconductor device where a plurality of electrodes are formed on a front face of a semiconductor chip; covering the front face of the semiconductor chip with a resin insulating film; covering all of an upper surface and side

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surfaces of the resin insulating film with a metal protective film so that the metal protective film contacts the resin insulating film and extends to a surface of the semiconductor chip; and providing an electrical connecting portion at a reverse face of the semiconductor chip, wherein the electrical connecting portion is connected to at least any of the plurality of electrodes on the front face of the semiconductor chip.

Any comments considered necessary by applicant must be submitted no later than the payment of the issue fee and, to avoid processing delays, should preferably accompany the issue fee. Such submissions should be clearly labeled "Comments on Statement of Reasons for Allowance."

Conclusion

Any inquiry concerning this communication or earlier communications from the examiner should be directed to Pamela E. Perkins whose telephone number is (571) 272-1840. The examiner can normally be reached on Monday thru Friday, 8:30am to 5:00pm.

If attempts to reach the examiner by telephone are unsuccessful, the examiner's supervisor, Zandra Smith can be reached on (571) 272-2429. The fax phone number for the organization where this application or proceeding is assigned is 571-273-8300.

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Information regarding the status of an application may be obtained from the Patent Application Information Retrieval (PAIR) system. Status information for published applications may be obtained from either Private PAIR or Public PAIR. Status information for unpublished applications is available through Private PAIR only. For more information about the PAIR system, see http://pair-direct.uspto.gov. Should you have questions on access to the Private PAIR system, contact the Electronic Business Center (EBC) at 866-217-9197 (toll-free).

PEP

Michael Trimin Primary Examiner

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